



2881
PATENT
Dkt. No.: 29273/559

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS: Yuko IWABUCHI, et al.
SERIAL NO. : 10/083,481
FILED : February 27, 2002
FOR : METHOD AND AN APPARATUS OF AN INSPECTION SYSTEM
USING AN ELECTRON BEAM
GROUP ART : 2881
EXAMINER : Jack I. Berman

TECHNOLOGY CENTER 2880

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ASSISTANT COMMISSIONER FOR
PATENTS AND TRADEMARKS
Washington D.C. 20231

RESPONSE TO OFFICE ACTION

Sir:

In response to the Office Action dated June 5, 2002, the due date being extended by the attached Petition for Extension of Time, please amend the above-identified application as follows:

IN THE CLAIMS:

Please amend claims 11 and 16 as follows:

- B1
11. (Amended) An inspection apparatus using an electron beam according to claim 10, further comprising:
a storage means for storing picture information conveyed by said electrical signal; and
a comparator for comparing pictures by using said picture information.

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